



# Aberration-Corrected Analytical Transmission Electron Microscopy

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# Aberration-Corrected Analytical Transmission Electron Microscopy

*Edited by*

Rik Brydson

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# Preface

Electron Microscopy, very much the imaging tool of the 20th Century, has undergone a steep change in recent years due to the practical implementation of schemes which can diagnose and correct for the imperfections (aberrations) in both probe-forming and image-forming electron lenses. This book aims to review this exciting new area of 21st Century analytical science which can now allow true imaging and chemical analysis at the scale of single atoms.

The book is concerned with the theory, background and practical use of transmission electron microscopes with lens correctors which can mitigate for, and to some extent control the effects of spherical aberration inherent in round electromagnetic lenses. When fitted with probe correctors, such machines can achieve the formation of sub-Angstrom electron probes for the purposes of (scanned) imaging and also importantly chemical analysis of thin solid specimens at true atomic resolution. As a result, this book aims to concentrate on the subject primarily from the viewpoint of scanning transmission electron microscopy (STEM) which involves correcting focused electron probes, but it also includes a comparison with aberration correction in the conventional transmission electron microscope (CTEM) where the principal use of correctors is to correct aberrations in imaging lenses used with parallel beam illumination.

The book has arisen from the formation in 2001 of the world's first aberration corrected Scanning Transmission Electron Microscope Facility (SuperSTEM <http://www.superstem.com>) at Daresbury Laboratories in Cheshire in the UK. This originally involved a consortium of the Universities of Cambridge, Liverpool, Glasgow and Leeds, the Electron Microscopy and Analysis Group of the Institute of Physics and the Royal Microscopical Society and, very importantly, funded by the Engineering and Physical Sciences Research Council (EPSRC). Following its inception we have organised four postgraduate summer schools in 2004,



2006, 2008 and 2010. The current text has evolved from these Summer Schools and aims to be a (detailed) handbook which although introductory, has sections which go into some depth and contain pointers to seminal work in the (predominantly journal) literature in this area. We envisage that the text will be of benefit for postgraduate researchers who wish to understand the results from or wish to use directly these machines which are now key tools in nanomaterials research. The book complements the more detailed text edited by Peter Hawkes (*Aberration corrected Electron Microscopy*, Advances in Imaging and Electron Physics, Volume 153, 2008).

The form of the handbook is as follows:

In Chapters 1 and 2, Peter Goodhew and Gordon Tatlock introduce general concepts in transmission electron microscopy and electron optics. In Chapter 3 Mick Brown details the development of the concept of the scanning transmission electron microscope which arose from the pioneering vision of Albert Victor Crewe, who was notably born in Bradford in the West Riding of Yorkshire and was a graduate of Liverpool University. Probe forming lens aberrations and their diagnosis and correction are investigated further by Andrew Bleloch and Quentin Ramasse in Chapter 4. The theory of STEM imaging is outlined by Pete Nellist in Chapter 5, whilst the detailed instrumentation associated with STEM is given by Alan Craven in Chapter 6. Analytical spectroscopy in STEM and the implications of STEM probe correction are introduced in Chapter 7 by Rik Brydson and Nicole Hondow. Mervyn Shannon reviews some examples and applications of aberration corrected STEM in Chapter 8. Finally, in Chapter 9, Sarah Haigh and Angus Kirkland make comparisons with image correction in CTEM. All authors have very considerable experience in transmission electron microscopy and also aberration correction from either a practical or applied perspective and we have attempted to integrate the various separate chapters together so as to form a coherent text with a common nomenclature detailed in Appendix B. Although I have taken the nominal lead in editing the text, it has been a joint effort by all authors.

Tremendous thanks must go to all those associated with SuperSTEM over the years notably Meiken and Uwe Falke, Mhari Gass, Kasim Sader, Bernhard and Miroslava Schaffer, Budhika Mendis, Ian Godfrey, Peter Shields, Will Costello, Andy Calder, Quentin Ramasse, Michael Saharan, Dorothea Muecke-Herzberg, Marg Robinshaw, Ann Beckerlegge and Uschi Bangert. Dedicated SuperSTEM students have been invaluable

and have included Sarah Pan, Paul Robb, Peng Wang, Linshu Jiang, Dinesh Ram, Sunheel Motru and Gareth Vaughan.

The final statements concerning the book should belong to Charles Lutwidge Dodgson (aka Lewis Carroll) who was born at Daresbury Parsonage less than a mile from the SuperSTEM laboratory and who famously wrote, '*Through the (aberration-corrected) Looking Glass*' and '*Alice in Wonderland*'

*'Begin at the beginning and go on till you come to the end: then stop.'*

But. ....

*'I don't believe there's an atom of meaning in it.'*

And. ....

*'What is the use of a book, without pictures or conversations?'*

Rik Brydson, Leeds 2011.

# Contents

List of Contributors	xi
Preface	xiii
<b>1 General Introduction to Transmission Electron Microscopy (TEM)</b>	<b>1</b>
<i>Peter Goodhew</i>	
1.1 What TEM Offers	1
1.2 Electron Scattering	3
1.2.1 Elastic Scattering	7
1.2.2 Inelastic Scattering	8
1.3 Signals which could be Collected	10
1.4 Image Computing	12
1.4.1 Image Processing	12
1.4.2 Image Simulation	13
1.5 Requirements of a Specimen	14
1.6 STEM Versus CTEM	17
1.7 Two Dimensional and Three Dimensional Information	17
<b>2 Introduction to Electron Optics</b>	<b>21</b>
<i>Gordon Tatlock</i>	
2.1 Revision of Microscopy with Visible Light and Electrons	21
2.2 Fresnel and Fraunhofer Diffraction	22
2.3 Image Resolution	23
2.4 Electron Lenses	25
2.4.1 Electron Trajectories	26
2.4.2 Aberrations	27
2.5 Electron Sources	30
2.6 Probe Forming Optics and Apertures	32
2.7 SEM, TEM and STEM	33

<b>3</b>	<b>Development of STEM</b>	<b>39</b>
	<i>L.M. Brown</i>	
3.1	Introduction: Structural and Analytical Information in Electron Microscopy	39
3.2	The Crewe Revolution: How STEM Solves the Information Problem	41
3.3	Electron Optical Simplicity of STEM	42
3.4	The Signal Freedom of STEM	45
3.4.1	Bright-Field Detector (Phase Contrast, Diffraction Contrast)	45
3.4.2	ADF, HAADF	45
3.4.3	Nanodiffraction	46
3.4.4	EELS	47
3.4.5	EDX	47
3.4.6	Other Techniques	48
3.5	Beam Damage and Beam Writing	48
3.6	Correction of Spherical Aberration	49
3.7	What does the Future Hold?	51
<b>4</b>	<b>Lens Aberrations: Diagnosis and Correction</b>	<b>55</b>
	<i>Andrew Bleloch and Quentin Ramasse</i>	
4.1	Introduction	55
4.2	Geometric Lens Aberrations and Their Classification	59
4.3	Spherical Aberration-Correctors	66
4.3.1	Quadrupole-Octupole Corrector	69
4.3.2	Hexapole Corrector	70
4.3.3	Parasitic Aberrations	72
4.4	Getting Around Chromatic Aberrations	74
4.5	Diagnosing Lens Aberrations	75
4.5.1	Image-based Methods	77
4.5.2	Ronchigram-based Methods	80
4.5.3	Precision Needed	85
4.6	Fifth Order Aberration-Correction	85
4.7	Conclusions	86
<b>5</b>	<b>Theory and Simulations of STEM Imaging</b>	<b>89</b>
	<i>Peter D. Nellist</i>	
5.1	Introduction	89
5.2	Z-Contrast Imaging of Single Atoms	90

5.3	STEM Imaging Of Crystalline Materials	92
5.3.1	Bright-field Imaging and Phase Contrast	93
5.3.2	Annular Dark-field Imaging	96
5.4	Incoherent Imaging with Dynamical Scattering	101
5.5	Thermal Diffuse Scattering	103
5.5.1	Approximations for Phonon Scattering	104
5.6	Methods of Simulation for ADF Imaging	106
5.6.1	Absorptive Potentials	106
5.6.2	Frozen Phonon Approach	107
5.7	Conclusions	108
<b>6</b>	<b>Details of STEM</b>	<b>111</b>
	<i>Alan Craven</i>	
6.1	Signal to Noise Ratio and Some of its Implications	112
6.2	The Relationships Between Probe Size, Probe Current and Probe Angle	113
6.2.1	The Geometric Model Revisited	113
6.2.2	The Minimum Probe Size, the Optimum Angle and the Probe Current	115
6.2.3	The Probe Current	115
6.2.4	A Simple Approximation to Wave Optical Probe Size	117
6.2.5	The Effect of Chromatic Aberration	117
6.2.6	Choosing $\alpha_{\text{opt}}$ in Practice	118
6.2.7	The Effect of Making a Small Error in the Choice of $\alpha_{\text{opt}}$	119
6.2.8	The Effect of $\alpha$ On the Diffraction Pattern	120
6.2.9	Probe Spreading and Depth of Field	122
6.3	The Condenser System	124
6.4	The Scanning System	126
6.4.1	Principles of the Scanning System	126
6.4.2	Implementation of the Scanning System	128
6.4.3	Deviations of the Scanning System From Ideality	128
6.4.4	The Relationship Between Pixel Size and Probe Size	130
6.4.5	Drift, Drift Correction and Smart Acquisition	131
6.5	The Specimen Stage	133
6.6	Post-Specimen Optics	135
6.7	Beam Blanking	136
6.8	Detectors	137
6.8.1	Basic Properties of a Detector	137

6.8.2	Single and Array Detectors	139
6.8.3	Scintillator/Photomultiplier Detector	139
6.8.4	Semiconductor Detectors	141
6.8.5	CCD Cameras	142
6.9	Imaging Using Transmitted Electrons	145
6.9.1	The Diffraction Pattern	145
6.9.2	Coherent Effects in the Diffraction Pattern	147
6.9.3	Small Angular Range – Bright Field and Tilted Dark Field Images	152
6.9.4	Medium Angular Range – MAADF	152
6.9.5	High Angular Range – HAADF	153
6.9.6	Configured Detectors	153
6.10	Signal Acquisition	154
	Acknowledgements	159
<b>7</b>	<b>Electron Energy Loss Spectrometry and Energy Dispersive X-ray Analysis</b>	<b>163</b>
	<i>Rik Brydson and Nicole Hondow</i>	
7.1	What is EELS and EDX?	164
7.1.1	Basics of EDX	164
7.1.2	Basics of EELS	166
7.1.3	Common Features For Analytical Spectrometries	168
7.2	Analytical Spectrometries in the Environment of the Electron Microscope	170
7.2.1	Instrumentation for EDX	170
7.2.2	EELS Instrumentation	174
7.2.3	Microscope Instrumentation for Analytical Spectroscopies	178
7.3	Elemental Analysis and Quantification Using EDX	182
7.4	Low Loss EELS – Plasmons, IB Transitions and Band Gaps	187
7.5	Core Loss EELS	191
7.5.1	Elemental Quantification	191
7.5.2	Near-Edge Fine Structure For Chemical and Bonding Analysis	195
7.5.3	Extended-Edge Fine Structure For Bonding Analysis	200
7.6	EDX and EELS Spectral Modelling	201
7.6.1	Total Spectrum Modelling	201

7.6.2	EELS Modelling of Near Edge Structures and also the Low Loss	201
7.7	Spectrum Imaging: EDX and EELS	202
7.8	Ultimate Spatial Resolution of EELS	206
7.9	Conclusion	207
8	<b>Applications of Aberration-Corrected Scanning Transmission Electron Microscopy</b>	<b>211</b>
	<i>Mervyn D. Shannon</i>	
8.1	Introduction	211
8.2	Sample Condition	212
8.3	HAADF Imaging	213
8.3.1	Imaging of Isolated Atoms	213
8.3.2	Line Defects (1-D)	219
8.3.3	Interfaces and Extended Defects (2-D)	220
8.3.4	Detailed Particle Structures (3-D)	226
8.3.5	Low-loss EELS	230
8.3.6	Core-loss EELS and Atomic-scale Spectroscopic Imaging	231
8.4	Conclusions	236
9	<b>Aberration-Corrected Imaging in CTEM</b>	<b>241</b>
	<i>Sarah J. Haigh and Angus I. Kirkland</i>	
9.1	Introduction	241
9.2	Optics and Instrumentation for Aberration- Corrected CTEM	243
9.2.1	Aberration-Correctors	243
9.2.2	Related Instrumental Developments	243
9.3	CTEM Imaging Theory	244
9.3.1	CTEM Image Formation	244
9.3.2	The Wave Aberration Function	246
9.3.3	Partial Coherence	252
9.4	Corrected Imaging Conditions	253
9.4.1	The Use of Negative Spherical Aberration	254
9.4.2	Amplitude Contrast Imaging	256
9.5	Aberration Measurement	256
9.5.1	Aberration Measurement From Image Shifts	256
9.5.2	Aberration Measurement from Diffraction Patterns	257

9.5.3	An Alternative Approach to Aberration Measurement	258
9.6	Indirect Aberration Compensation	258
9.7	Advantages of Aberration-Correction for CTEM	259
9.8	Conclusions	259
	Acknowledgements	260
Appendix A:	Aberration Notation	263
Appendix B:	General Notation	267
Index		275



# 1

## General Introduction to Transmission Electron Microscopy (TEM)

Peter Goodhew

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### 1.1 WHAT TEM OFFERS

Transmission electron microscopy is used to reveal sub-micrometre, internal fine structure in solids. Materials scientists tend to call this *microstructure* while bioscientists usually prefer the term *ultrastructure*. The amount and scale of the information which can be extracted by TEM depends critically on four parameters; the resolving power of the microscope (usually smaller than 0.3 nm); the energy spread of the electron beam (often several eV); the thickness of the specimen (almost always significantly less than 1  $\mu\text{m}$ ), and; the composition and stability of the specimen. The first and second of these depend largely on the depth of your pocket – the more you spend, the better the microscope parameters. The third is usually determined by your experimental skill while the last depends on luck or your choice of experimental system. The slim book by Goodhew *et al.* (Goodhew, Humphreys and Beanland,

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